

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Hwang et al.

Examiner: Rosasco, Stephen D

Serial No: 10/827,556

Group Art Unit: 1756

Filed: April 19, 2004

Docket: 8028-43 (SPX200304-0016US)

**FOR: PHOTOMASK FOR FORMING PHOTORESIST PATTERNS
REPEATING IN TWO DIMENSIONS AND METHOD OF FABRICATING THE
SAME**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

Sir:

This Amendment is submitted in response to the April 5, 2007 Office Action issued by the United States Patent and Trademark Office in connection with the above-identified application.